Listing of Claims

- 1. (Currently Amended) An ultracapacitor, comprising:
 - a semiconductor substrate;

N conductive layers on the substrate, where N > 2; and

N-Idielectric layers formed between the conductive layers respectively, wherein even numbered ones of the N conductive layers are connected to a first voltage and odd numbered ones of the N conductive layers are set to a second voltage.

- 2. (Canceled)
- 3. (Currently Amended) The ultracapacitor of claim 1 [[2]], wherein the N conductive layers store a distribution of charge corresponding to a difference between the first and second voltages.
- 4. (Original) The ultracapacitor of claim 1, wherein a uniform charge distribution is stored among the N conductive layers.
- 5. (Original) The ultracapacitor of claim 1, wherein a non-uniform charge distribution is stored among the N conductive layers.
- 6. (Currently Amended) An [[The]] ultracapacitor of claim-1 comprising:

 a semiconductor substrate;

N conductive layers on the substrate, where N > 2; and

N-1dielectric layers formed between the conductive layers respectively, wherein the N conductive layers have a same width.

- 7. (Original) The ultracapacitor of claim 1, wherein at least two of the N conductive layers have different widths.
- 8. (Original) The ultracapacitor of claim 7, wherein the N conductive layers include at least two adjacent conductive layers that have different widths.
- 9. (Currently Amended) An [[The]] ultracapacitor of claim-1 comprising:

 a semiconductor substrate;

N conductive layers on the substrate, where N > 2; and

N-1dielectric layers formed between the conductive layers respectively, wherein the N conductive layers include adjacent pairs of conductive layers and wherein the conductive layers in each pair have a same width.

- 10. (Original) The ultracapacitor of claim 9, wherein the widths of the conductive layers in each pair are different from the widths of the conductive layers in every other pair.
- 11. (Original) The ultracapacitor of claim 1, wherein the N conductive layers are equally spaced.
- 12. (Currently Amended) An [[The]] ultracapacitor of claim 1 comprising:

 a semiconductor substrate;

N conductive layers on the substrate, where N > 2; and

N-1dielectric layers formed between the conductive layers respectively, wherein the N conductive layers are spaced differently.

13. (Currently Amended) An [[The]] ultracapacitor of claim-1 comprising:

a semiconductor substrate;

N conductive layers on the substrate, where N > 2; and

N-1dielectric layers formed between the conductive layers respectively, wherein the conductive and dielectric layers form a plurality of capacitors connected in parallel.

- 14. (Original) The ultracapacitor of claim 1, wherein the N-1 dielectric layers are at least partially made an oxide of hafnium, and oxide of zirconium, and a barium titanate powder.
- 15. (Original) The ultracapacitor of claim 14, wherein the oxide of hafnium has a dielectric constant k = 15, the oxide of zirconium has a k = 22, and the barium titanate powder has a k = 230.
- 16. (Original) An integrated circuit, comprising:
 - a first ultracapacitor; and
 - a second ultracapacitor connected in series to the first ultracapacitor.
- 17. (Original) The circuit of claim 16, further comprising:a semiconductor substrate supporting both the first and second ultracapacitors.
- 18. (Original) The circuit of claim 16, wherein the first and second ultracapacitors each include:
 - a semiconductor substrate,

N conductive layers on the substrate, where N > 2, and

N-1 dielectric layers formed between the conductive layers respectively.

- 19. (Original) The circuit of claim 18, wherein the N conductive layers form a plurality of capacitors connected in parallel.
- 20. (Original) The circuit of claim 16, wherein the first and second ultracapacitors are formed on stacked substrates.
- 21-24 (Canceled)
- 25. (Currently Amended) A semiconductor die, comprising:

N conductive layers on the substrate, where N > 2; and

N-1 dielectric layers formed between the conductive layers respectively,

wherein the conductive and dielectric layers store a charge corresponding to a predetermined voltage, wherein even numbered ones of the N conductive layers are connected to a first voltage and odd numbered ones of the N conductive layers are set to a second voltage.

- 26. (Canceled)
- 27. (Currently Amended) The die of claim 25 [[26]], wherein the N conductive layers store a distribution of charge corresponding to a difference between the first and second voltages.

28. (Currently Amended) A semiconductor [[The]] die of claim 25, comprising:

N conductive layers on the substrate, where N > 2; and

N-1 dielectric layers formed between the conductive layers respectively,

wherein the conductive and dielectric layers store a charge corresponding to a predetermined voltage and form a plurality of capacitors connected in parallel.

- 29. (Currently Amended) The die of claim <u>28</u> [[25]], wherein the parallel connection of capacitors powers a processor.
- 30. (Currently Amended) The die of claim 28 [[25]], wherein the parallel connection of capacitors is included in one of a processor, a memory, a cache, a chipset, and an interface.